



IPW
PATENT
Customer No. 22,852
Attorney Docket No. 04788.0247-01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Yasuhiro OMURA) Group Art Unit: 2851
Application No.: 10/726,494) Examiner: Hung Nguyen
Filed: December 4, 2003) Confirmation No.: 7548
For: PROJECTION OPTICAL SYSTEM, EXPOSURE)
APPARATUS INCORPORATING THIS)
PROJECTION OPTICAL SYSTEM, AND)
MANUFACTURING METHOD FOR MICRO)
DEVICES USING THE EXPOSURE APPARATUS)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT

In reply to the Office Action dated October 4, 2004, the shortened statutory period for response having been extended through January 4, 2005 by a Petition for Extension of Time for two months and fee payment filed concurrently herewith, Applicant respectfully requests the Examiner to enter the following amendments to the application:

Amendments to the Abstract are shown at page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims beginning on page 3 of this paper.

Remarks are reflected at page 10 of this paper.

Attachments to this paper include a Replacement Abstract.